

Patent Abstracts of Japan

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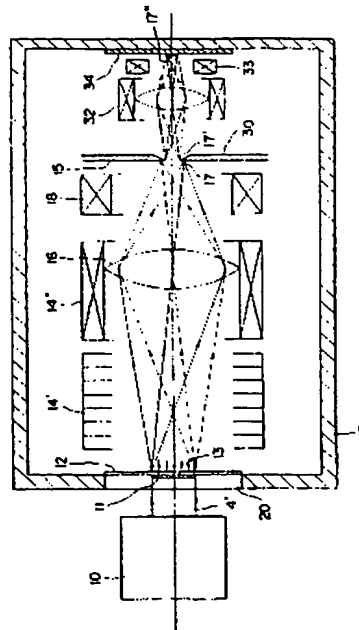
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TITLE : ELECTRON IMAGE PROJECTION
FORMING DEVICE



ABSTRACT : PURPOSE: To enable element electron images in various shapes and size to be made by accelerating electron speed by a method wherein previously and optically patterned light is projected on a photoelectric surface so as to form an electron source in surface corresponding to the pattern and accelerating the generated electrons for the formation of the electron images in surface on a projection surface.

CONSTITUTION: When an optical pattern is projected on a photoelectric surface 12 using an optical pattern projecting means 10, photoelectrons are radiated in surface from the positions on the photoelectric surface 12 corresponding to the pattern. These photoelectrons accelerated by an accelerating means 14 advance to a projection surface 15. Electron images are formed by projection on the projection surface 15 using a projecting means 14, i.e., an electron lens 16 comprising a magnetic or electric field. In such a process, an electron deflecting means can be actuated so that the overlapped parts may be controlled to make electron images in various shapes and sizes.

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